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Epitaxial growth of BiFeO<sub>3</sub> thin films on  $SrTiO_3/Si$  substrates<sup>1</sup> RYAN LAUGHLIN, DANIEL CURRIE, GOKUL RADHAKRISHNAN, WEERAS-INGHE PRIYANTHA, ROCIO CONTRERAS-GUERERRO, RAVINDRANATH DROOPAD, NIKOLETA THEODOROPOULOU, Texas State University - San Marcos — We are using molecular beam epitaxy (MBE) to grow  $BiFeO_3$  (BFO) thin films.  $SrTiO_3$  (STO) on Si is used as a virtual substrate to enable the growth of BFO. Commensurate growth of STO on Si using MBE has been achieved by using co-deposition with the fluxes adjusted for stoichiometric growth and the growth rate is determined using RHEED intensity oscillations. The native oxide of the Si substrates is removed in-situ by deoxidation at around 750 °C using a flux of Sr. The substrate is cooled to  $500\ ^{\circ}$ C and additional Sr is added to form template with a (2x1) surface structure. BFO is then deposited on well-characterized STO (2-20nm thick) on Si using Fe and oxygen plasma with an overpressure of Bi flux- the growth rate being controlled by the incoming Fe flux. The RHEED pattern taken during deposition of BFO shows 2-D growth front with a 6-fold surface reconstruction. The structural and magnetic properties of the BFO samples have also been measured.

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